



MEMC 98-4650(2293)  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Gregory Michael Wilson et al.

Art Unit 1765

Serial No. 09/608,302

Filed June 30, 2000

Confirmation No. 9819

For A METHOD AND APPARATUS FOR FORMING A SILICON WAFER WITH A  
DENUDED ZONE

Examiner Robert M. Kunemund

October 23, 2003

**AMENDMENT D**

TO THE ASSISTANT COMMISSIONER FOR PATENTS,

SIR:

In response to the Office action dated June 23, 2003, please make the following amendments and consider the following remarks and arguments set in this Amendment D.

10/28/2003 KBETEM1 00000048 09608302

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